



# 제25회 한국반도체학술대회

The 25<sup>th</sup> Korean Conference on Semiconductors

2018년 2월 5일(월)-7일(수), 강원도 하이원리조트 컨벤션 호텔

2018년 2월 7일(수), 09:00-10:30

Room K (육백II, 6층)

## Q. Metrology, Inspection, and Yield Enhancement 분과

### [WK1-Q] Inspection & Yield Enhancement

WK1-Q-1 09:00-09:15	<b>Development of UV Line Scanning System for Detecting Safer Defect of XXnm Size</b> Han Gyeong Oh <sup>1</sup> , Han Mo Yang <sup>1</sup> , Seong Chul Oh <sup>2</sup> , Seung Yong Chu <sup>2</sup> , and Jai Soon Kim <sup>1</sup> <i><sup>1</sup>NEMO Lab, Department of Physics, Myongji University, <sup>2</sup>AUROS Technology</i>
WK1-Q-2 09:15-09:45	<b>[초청]</b> <b>Micro-Thermography and Applications</b> Ki Soo Chang <sup>1</sup> , Dong Uk Kim <sup>1</sup> , Byung-Seon Chun <sup>2</sup> <i><sup>1</sup>Division of Scientific Instrumentation, Korea Basic Science Institute, <sup>2</sup>Nanoscope Systems Institute</i>
WK1-Q-3 09:45-10:00	<b>Design of the Hi-Efficiency Dark-Field Illumination System Using Anamorphic Optics for Near-Field Microscope</b> Sunseok Yang <sup>1</sup> , Woojun Han <sup>1</sup> , Seungyoung Chu <sup>2</sup> , Seungchul Oh <sup>2</sup> , Jaisoon Kim <sup>1</sup> <i><sup>1</sup>Department of Physics, Myongji University, <sup>2</sup>AUROS technology</i>
WK1-Q-4 10:00-10:15	<b>Early Yield Ramping Up Methodology through Multi-Layers Simulation with Real Process Variation</b> Jin Kim, Byung-Moo Kim, JunSu Jeon, Ki-Heung Park, Jae Hyun Kang, SeungWeon Paek, and ByungMoo Song <i>Technology Development, Foundry, Samsung Electronics</i>
WK1-Q-5 10:15-10:30	<b>Yield 개선을 위한 Wafer Edge Weak Point 개선 System 구축 산포분석에 의한 검증과 2Defect Library System 의 활용</b> Hyunwoo Kang, Sangwoo Kim, Sunkeun Ji, Sookyeong Jeong, Minwoo Park, Hun Lee, Jungchan Kim, Cheolkyun Kim, Hyunjo Yang <i>R&amp;D Division, SK Hynix</i>